





ABSTRACT:

**"A Multi-Parameter Microchip"**

Microchips, for simultaneous micro-gravimetric sensing and surface plasmon resonance (SPR) sensing, or for simultaneous micro-gravimetric sensing and optical sensing, comprising first and second electrodes on either side of a transparent piezoelectric substrate, at least one of said electrodes being formed of a film of a conductive, substantially transparent material; and methods for fabricating said microchips.

[Figure 1]